



Real-Time AMC Monitoring

For Semiconductor Fabrication Processes and Facilities



Applications

- ✓ FOUP monitoring
- ✓ Mobile AMC measurements
- ✓ Stationary (multi-port) AMC measurements

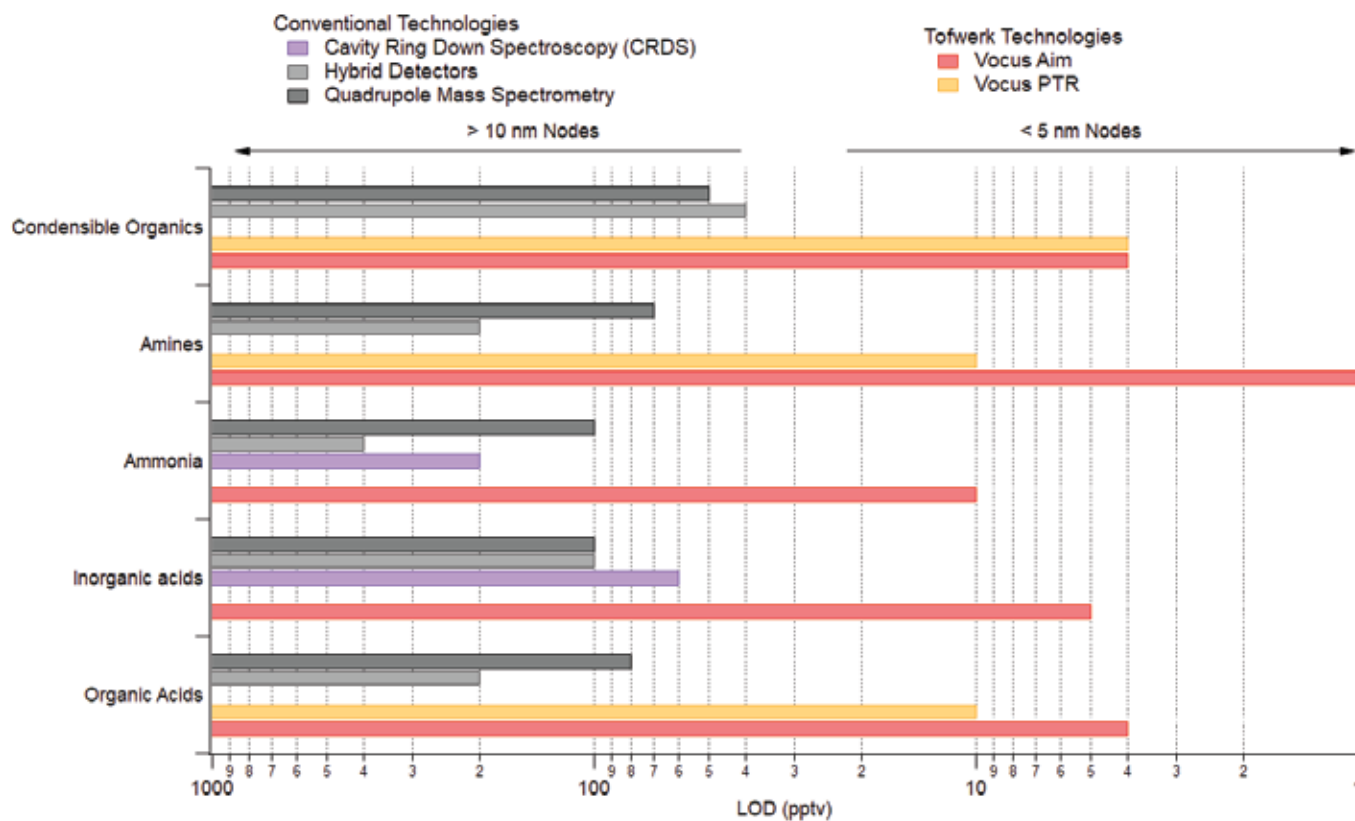
Features

- ✓ Real-time online measurements at pptV limits of detection.
- ✓ High mass resolving power for accurate identification.
- ✓ Automated fast switching between reagent ions for quantification of molecular acids, bases, condensables and VOCs.
- ✓ Compact design with flexible inlet configuration.
- ✓ Automated calibration, zero-air measurement, and data reporting.

The ideal solution for comprehensive AMC monitoring

The Vocus CI-TOF provides manufacturers with a comprehensive solution for the detection of AMCs in FOUP, mobile, and multi-port applications inside the fab, providing critical input in order to reach and maintain a 'VOC-free' fabrication environment.

Comparing the Vocus CI-TOF to Other Technologies



A solution for every fab application

The Vocus CI-TOF product line comes in a variety of configurations to meet the needs of your required analysis. In addition to R&D instrumentation with state-of-the-art resolution for the most complex gas mixtures, the Vocus product line includes compact models for mobile versatility and specialized models for complete coverage when monitoring acids, bases, condensables and VOCs.

Contact our team today to get a quote or schedule a demo.

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